Onpria A NUMERIC MODEL FOR THE IMAGING MECHANISM OF METAL OXIDE EUV RESISTS

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Negative Tone Resist Chemistries in Organic Polymers

Direct crosslinking of polymer [poly(4-Cl-styrene)]



Polarity change [t-BOC, NTD resists]



Chain polymerization [Riston, SU-8]



Crosslinking by multifunctional additive [CGR, bis-azide]



None of these describe the primary imaging mechanism in MOx resists

A Generic Imaging Model for MOx Resist Systems

- Basic approach :
 - Minimalist description of chemistry and physics
 - Follow progression of radiation and condensation chemistry
- Resist building block notation
 - **Core** molecule / framework / cluster / nanoparticle
 - Multiple radiation-sensitive ligands L per core
 - Condensation of active site A formed upon ligand radiolysis leads to Oxo-Network formation





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Analogue of Sol-Gel Process

- Characteristics of sol-gel chemistry:
 - Site activation by catalyst
 - Simultaneous condensation and further activation
 - Complex mixture of intermediate species
 - Polymerization proceeds toward oxo-network formation
- MOx imaging model:

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- Site activation by <u>radiation chemistry</u>
- Solid phase condensation of neighboring cores
- Complex mixture of intermediate species
- Polymerization proceeds toward oxo-network formation





Overview of Modeling Process

A Molecular-Scale Description

- 3D array of individual molecules
- Track individual events
- Statistical effects accounted for

Model Inputs:

- Molecular volume
- Number of radiation-sensitive ligands per core
- EUV absorption coefficient
- "Quantum yield":
- Definition: number of ligands fragmented per photon absorbed
- In model, use the number of electrons generated per photon as a proxy
- "Radiochemical blur length":
- Definition: distance scale over which chemical change may occur from point of photon absorption
- In model, use "electron blur" length as a proxy
- Film thickness
- Exposure dose





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Step 1 - EUV Absorption

A stochastic implementation of Beer's Law

Protocol:

- Divide film surface into sub-areas
- Distribute impinging photons onto surface
- Distribute photons in sublayers according to probabilities

Example

- molecular volume 2.3 nm³
- 15 mJ/cm² flood exposure
- 1928 impinging photons, 662 absorbed





Step 2 - Secondary Electron Generation

Apply experimentally derived electron yield and blur length to photon absorption distribution

Protocol:

- Each photon generates on average *n* electrons
- Allow electrons to stochastically "diffuse" from point of photon absorption
- Terminate electron diffusion when average diffusion distance = blur length

Example

- molecular volume 2.3 nm³
- 15 mJ/cm² flood exposure
- avg 8 electrons per photon
- 1.4 nm electron blur length





Step 3 – Primary Photoproduct Distribution

- Allow electron distribution to interact with resist material
- Assumptions:
 - Each ligand is chemically equivalent
 - Reactivity is unaffected by degree of decomposition
- A complex product mix results: e.g., for a tetra-substituted core



Photoproduct distribution is a function of dose



An Example Photoproduct Spatial Distribution

Hypothetical MOx resist with 12 radiation-sensitive ligands per core, EUV flood exposure 15 mJ/cm² dose

0 active sites



6 active sites



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7 active sites



2 active sites



8 active sites



3 active sites

9 active sites



4 active sites



10 active sites





5 active sites



Photoproduct Distribution Depends on Dose



Impact of Photoproduct Distribution

Role of photoproduct in condensation depends on structure:





Photoproduct Distribution Depends on Dose



Step 4 – Condensation of Primary Photoproducts

- Calculate the evolution of oxo-networks
 - Each core starts with a set number of active sites
 - Condensation only if core and neighbor both have an active site
 - Condensation forms one oxo-bond and consumes two active sites
- Protocol:
 - a) Initialize with photoproduct distribution
 - b) Select a core
 - c) Core and neighbor both have active sites?
 - i. Form oxo-bond
 - ii. Subtract active sites
 - d) Repeat (b) and (c) until probability of reaction is zero

Result: Population of oxo-network polymers







Step 5 – Analyze Topology of Condensation Products

Protocol:

- a) Scan through array of cores looking for bonds
- b) If a core is bonded to any of its neighbors
 - 1. Check each bonded neighbor to see if it is bonded to its neighbors
 - 2. Recursively following the bonding including branches and crosslinks
- c) Continue scan until every core has been visited



Result: 3D map and population distribution of oxo-network polymers



Condensation Product Distribution vs Dose



Calculate Resist Contrast for a Real Resist

Inpria experimental MOx resist system

- 1. Estimate quantum yield and blur length from experimental data
- 2. Use model to calculate condensation products vs dose
- 3. Apply binary dissolution process
 - Only condensation products in direct contact with the substrate are insoluble



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Imaging - Chemical Latent Images NXE 3300, Dipole illumination, 16 nm line/32 nm pitch



20 mJ/cm²







15 mJ/cm²

Calculated Line-Space Images

NXE 3300, Dipole illumination, 16 nm line/32 nm pitch







Calculated vs Experimental Image : 24 nm pitch



Imaged using EUV-IL tool (Paul Scherrer Institut)



Summary

Simple chemical description of MOx resist

Photo-induced condensation of **multifunctional** cluster

EUV exposure chemistry data from Inpria MOx resist test vehicles

General **stochastic simulation** process

Quantitative link between photochemistry and imaging

Contrast originates from non-linear **oxo-network** formation

Lithographic predictions consistent with experimental observations

Potentially applicable to many resist systems

